First investigation of silicon microstrips for the CMS tracker upgrade using edge-TCT

Marcos Fernández García (IFCA-Santander)

On behalf of the CMS tracker collaboration

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M. Moll, M. Gabrysch, H. Neugebauer, N. Pacifico CERN

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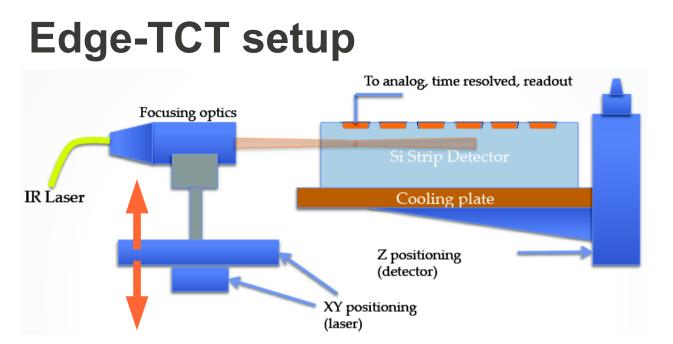
 \rightarrow eTCT intro

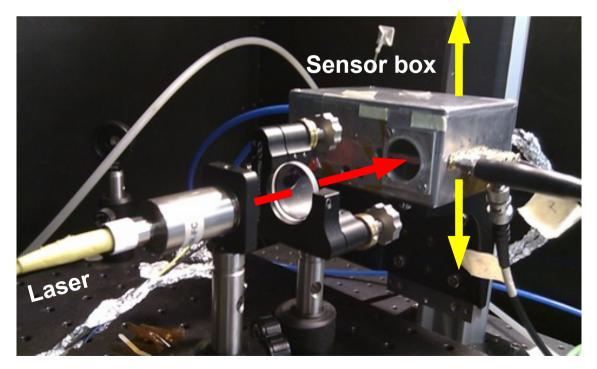
 \rightarrow Motivation of this study

 \rightarrow Effect of sensor coupling and laser power

 \rightarrow Results on unirradiated HPK detectors

21st RD50 Workshop, CERN, Geneva





• Charge carriers created at **selected depth** with respect to strips.

• Sensor properties can be studied **as a function of depth**.

• **Spatial resolutio**n given by laser width (vertical). Measurements averaged over strip width.

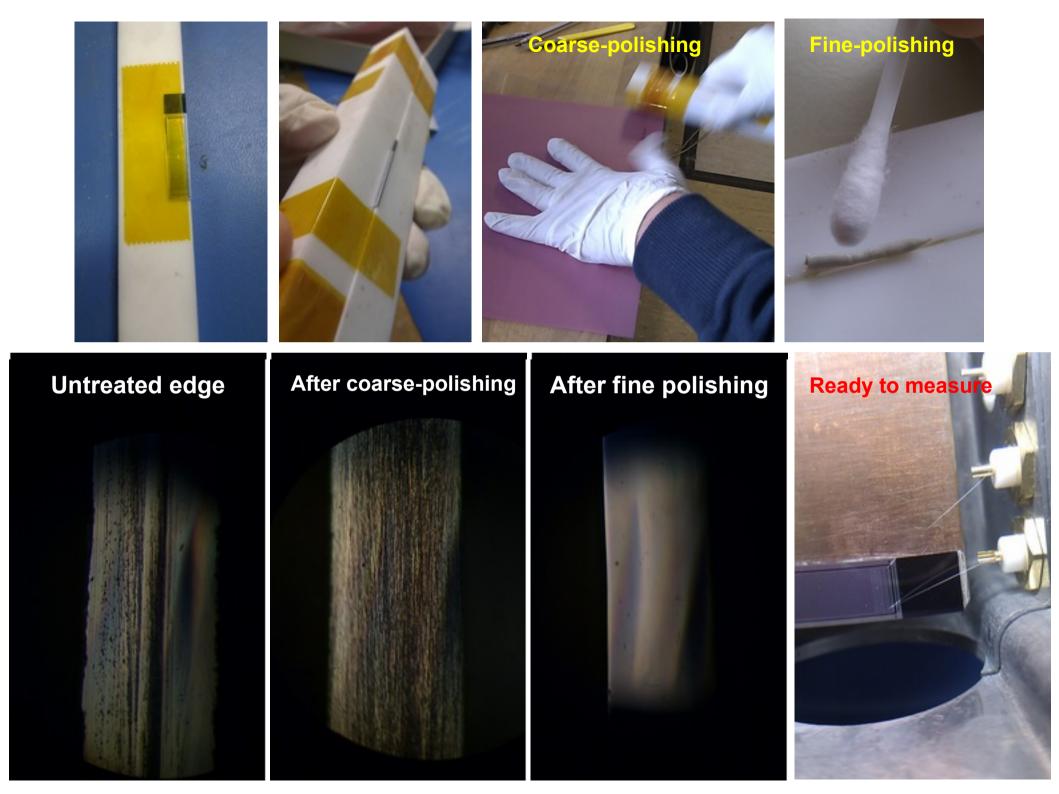
• One strip readout only.

• Setup@CERN was built by N. Pacifico during his PhD.

Featuring:

- \rightarrow 80 ps FWHM laser 1060 nm
- \rightarrow XYZ motion
- \rightarrow T controlled measurements
- \rightarrow In-situ annealing

• DAQ by CERN SSD (N.Pacifico, M.Gabrysch, I.Dolenc)



Motivation of this study

• Study baby strip detectors (320 µm physical thickness) from CMS HPK campaign using eTCT:

 \rightarrow Very useful to evaluate detector properties as a function of depth \rightarrow Very useful to picture how radiation damage develops in the bulk

• **Trapping** can be different at different depths: $\tau = \tau(z)$ (for instance because $N_{eff} = N_{eff}(z)$). A combined TCT + eTCT method has been proposed within the CMS HPK campaign to obtain the trapping time profile $\tau(z)$ for irradiated detectors:

 \rightarrow eTCT is used to **measure the drift velocity profile** in a **strip** detector

 \rightarrow Drift velocity profile **fed into red TCT simulation** (see T. Pöhlsen, RD50 Bari 2012), convoluted with electronics transfer function.

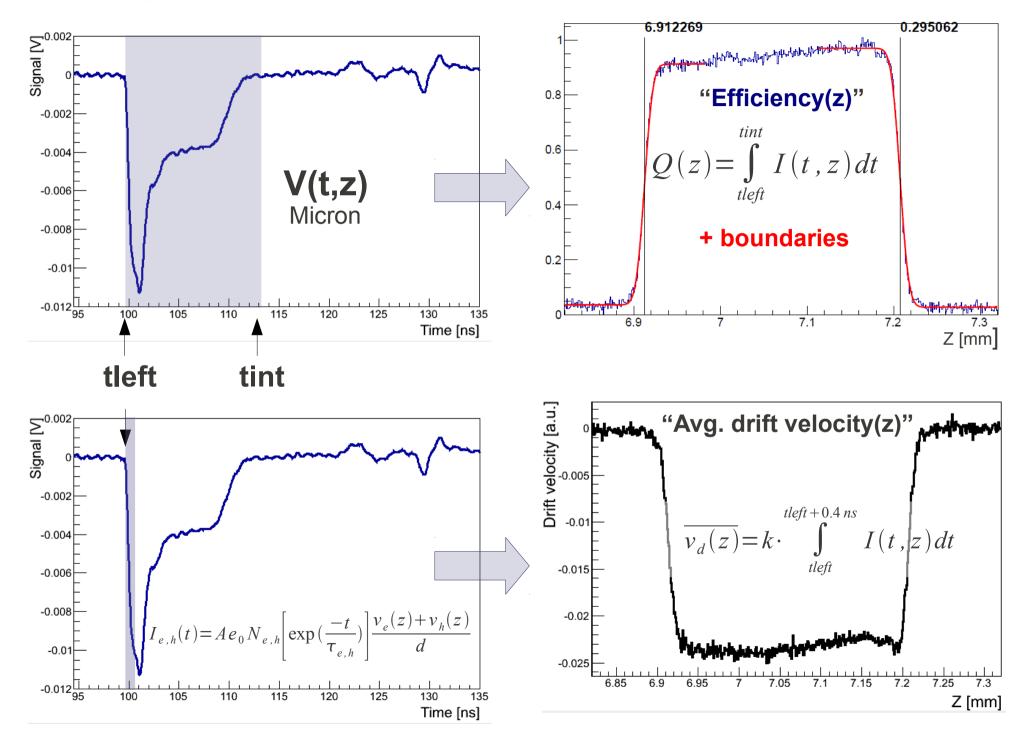
 \rightarrow **Diode** from same family as strip detector is **TCT measured**. Trapping is tuned in the simulation and result compared to measurement.

• Fluences to be addressed:

- \rightarrow Unirradiated
- \rightarrow 3e14 n_{eq}/cm² protons
- \rightarrow 1e15 n_{er}/cm² protons

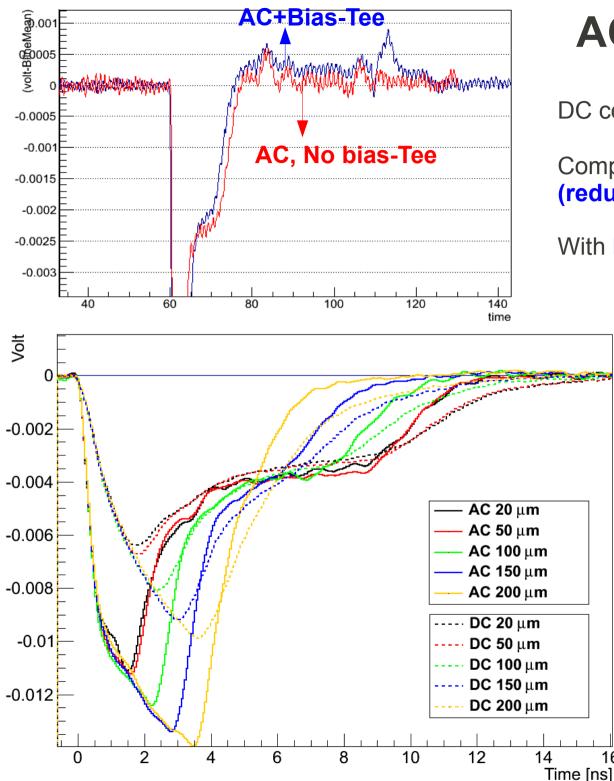
 $(\leftarrow$ This work)

Analysis of eTCT pulses



Common considerations to all measurements:

- AC or DC coupling
- What laser power ?



AC coupled detectors

DC coupling \Rightarrow Bias-Tee (Cc=2.2 nF) needed

Compared AC-coupled detector with Bias-T (redundant) with AC-coupled without it .

With **Bias-T**, undershoot is more noticeable.

Same detector AC or DC coupled

DC has Bias-tee in between the sensor and the amplifier. No undershoot.

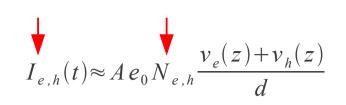
AC risetime is faster

Micro

16

Laser power: drift velocity

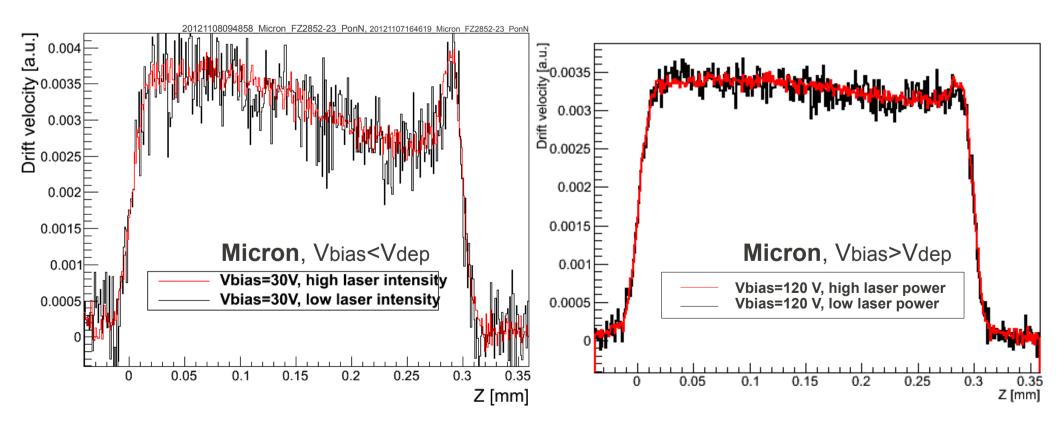
Drift velocity must be independent of laser intensity.



We do not measure the number of injected photons $N \Rightarrow$ Plots are still given in arbitrary units.

Higher laser intensity \rightarrow better S/N ratio

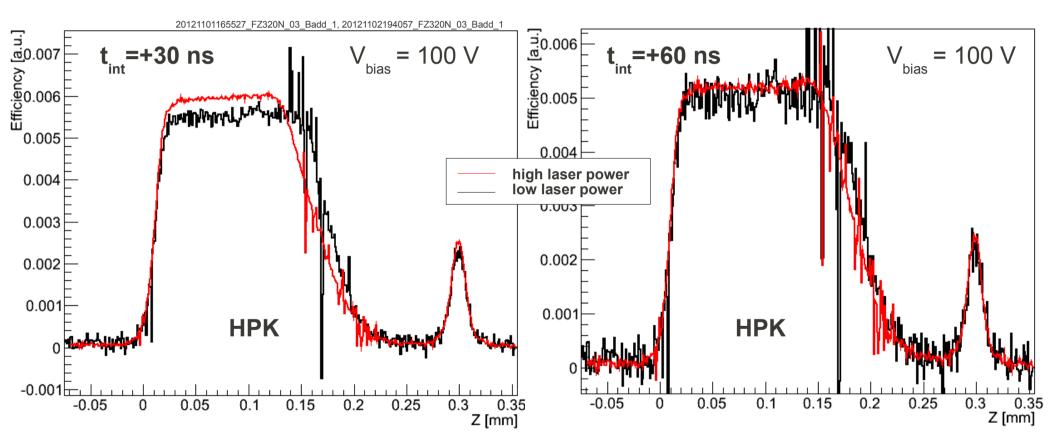
Normalized drift velocity identical for high and low laser intensity



Laser power: efficiency

Efficiency defined as $Q(z) = \int_{tleft}^{+tint} I(t, z) dt$ depends on laser intensity (and integration time)

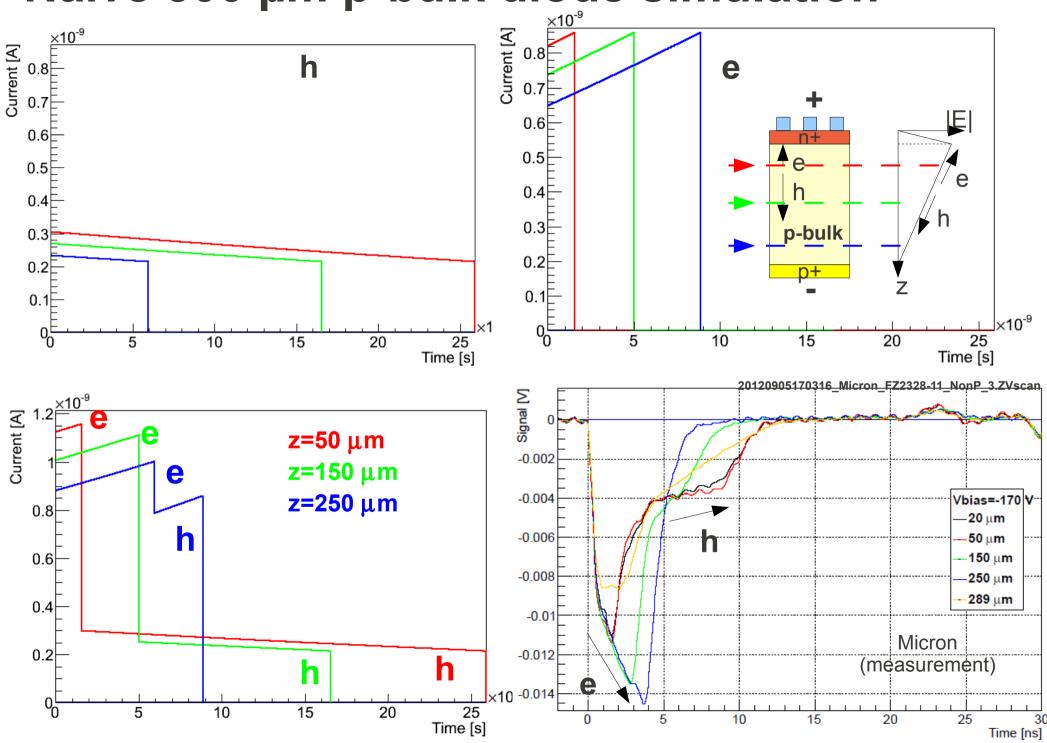
Normalized efficiency at high and low laser power coincides (for long integration time)



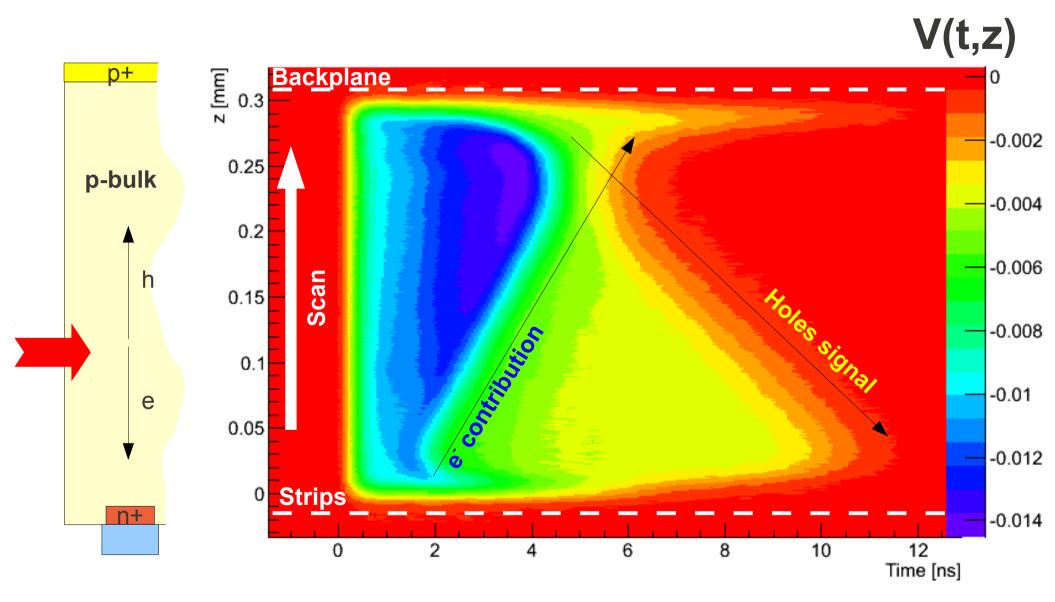
Since calculated efficiencies at low and high laser power coincide, this indicates we are very likely **not in plasma regime**

Photodiode will be added to estimate number of injected photons

Naïve 300 µm p-bulk diode simulation

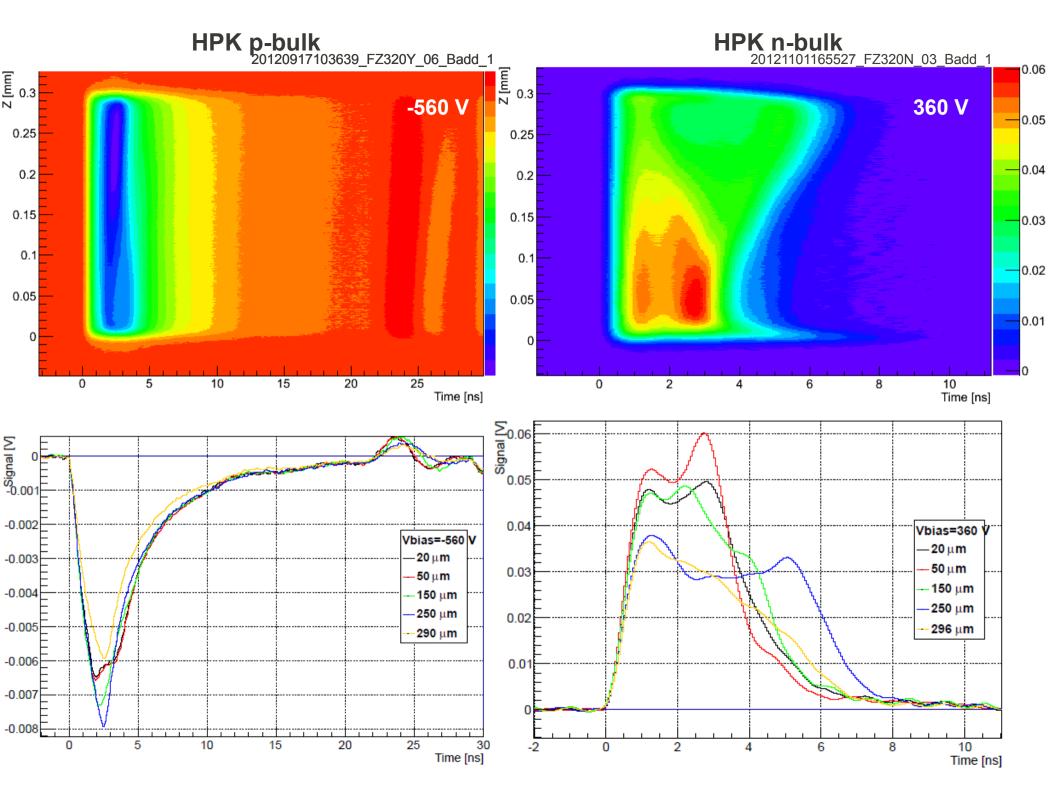


Micron: V(t,z) for a full Z scan (p bulk)

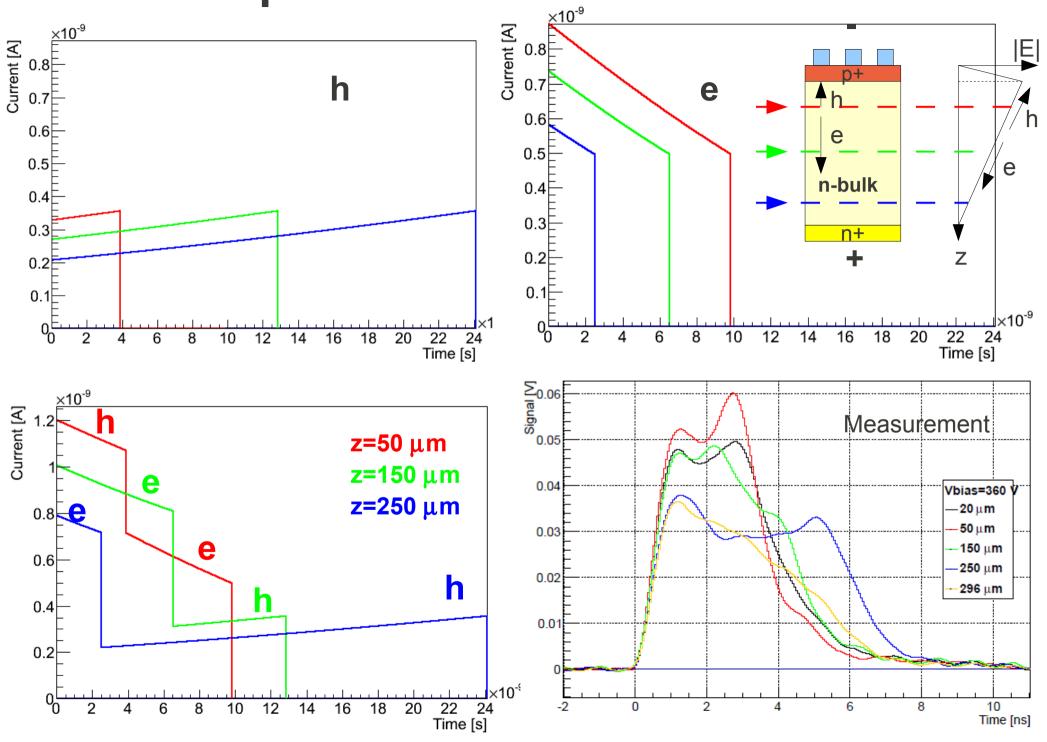


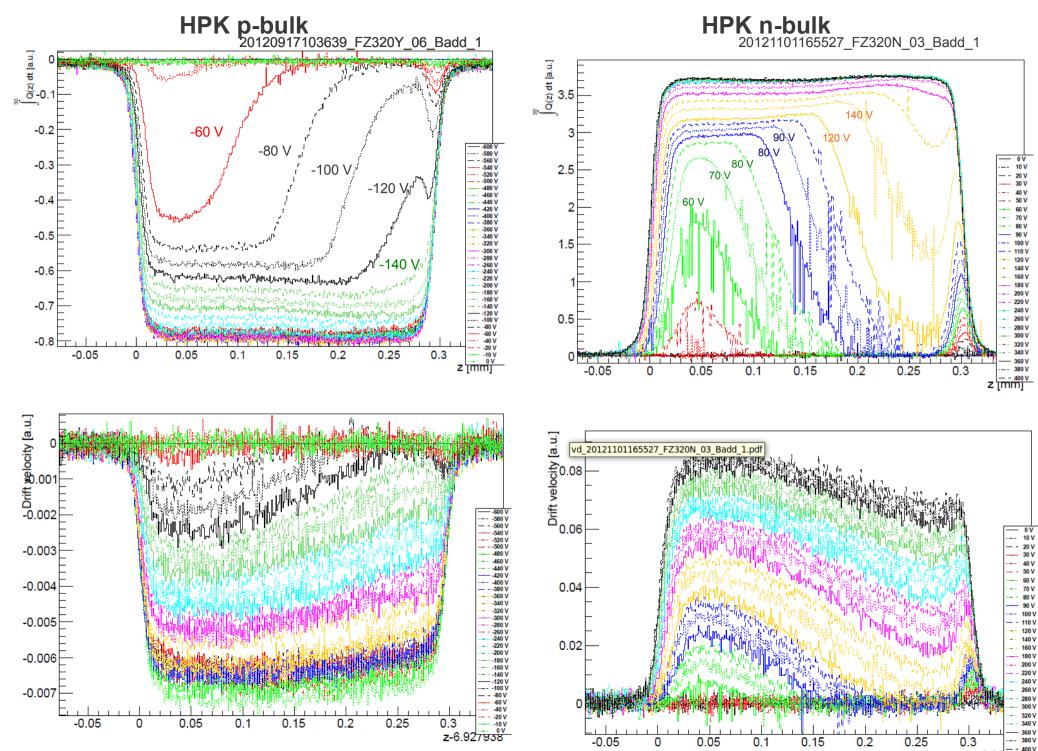
Contribution of electrons and holes clearly seen

Measurements of unirradiated p-bulk and n-bulk Hamamatsu detectors for CMS upgrade



Naïve 300 µm n-bulk diode simulation





.5 z-6.869968

Conclusions

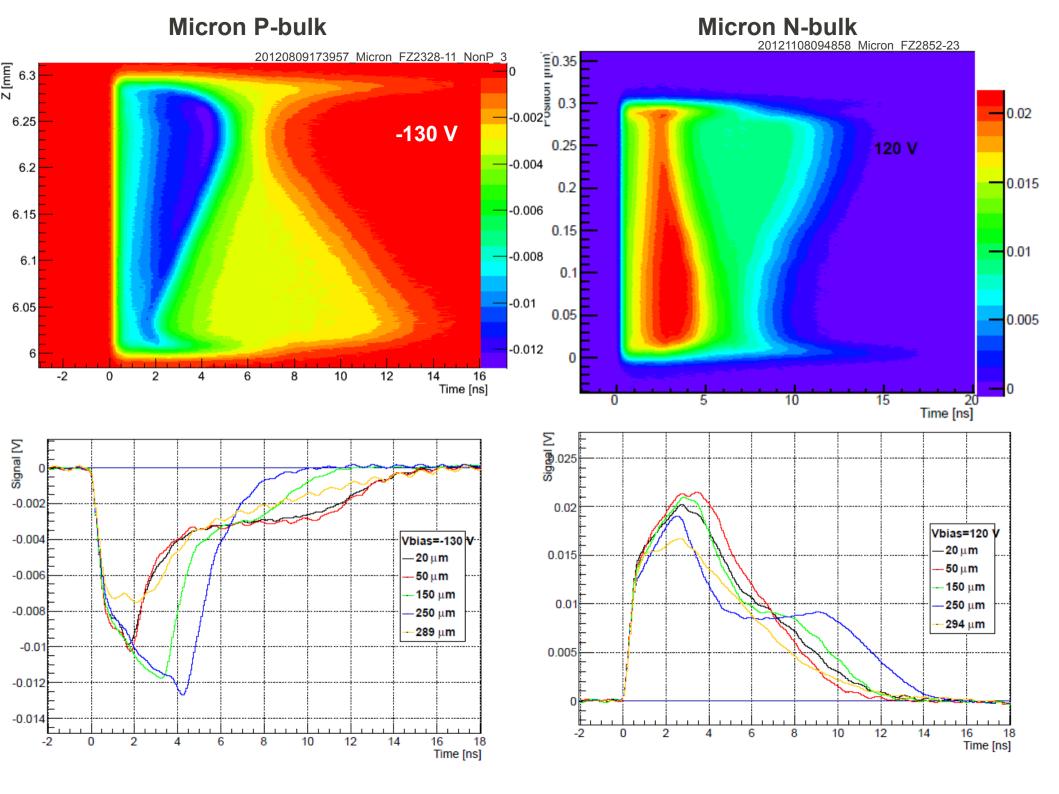
- Mini-strip sensors from CMS HPK campaign are being measured using eTCT.
 Measurements done at SSD lab at CERN
- Former published work on eTCT Micron detectors taken as guideline:
 - CERN setup validated measuring p-bulk micron detectors
- Detectors are AC coupled
- Normalized drift velocity & efficiency used to compare measurements at different laser powers
- e-h contributions to I(t):

Micron:		HPK:	
	clear e-h contribution. less direct to interpret, but visible	•	e-h contribution washed out visible

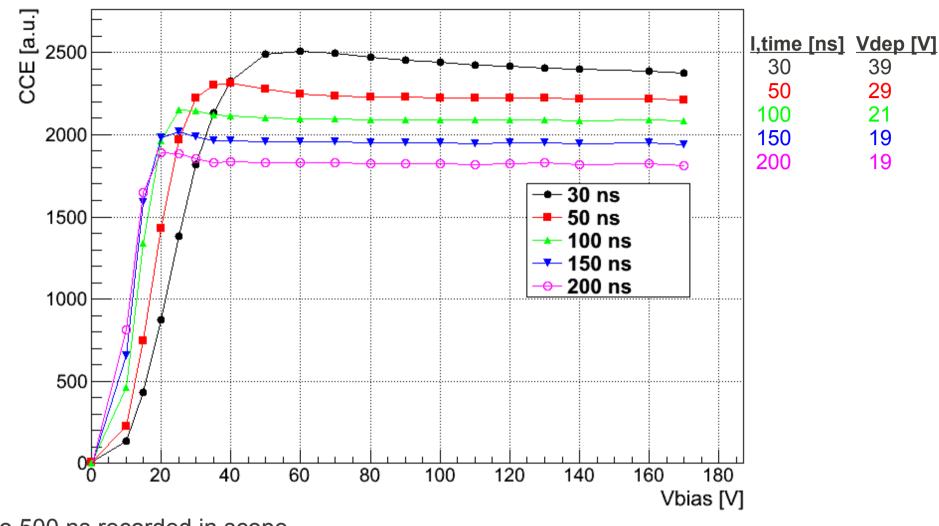
• HPK detectors show flat efficiency profiles after depletion. Effect of deep diffusion seen as double junction. Only 3 detectors measured for the moment.

• Next steps: measure (and irradiate) more detectors and extend study to other materials within the scope of CMS HPK campaign.

Thanks to I. Dolenc for help at the beginning of this work Thanks to I. McGill & F. Manolescu (bonding lab) for bonding of detectors here presented BACKUPS



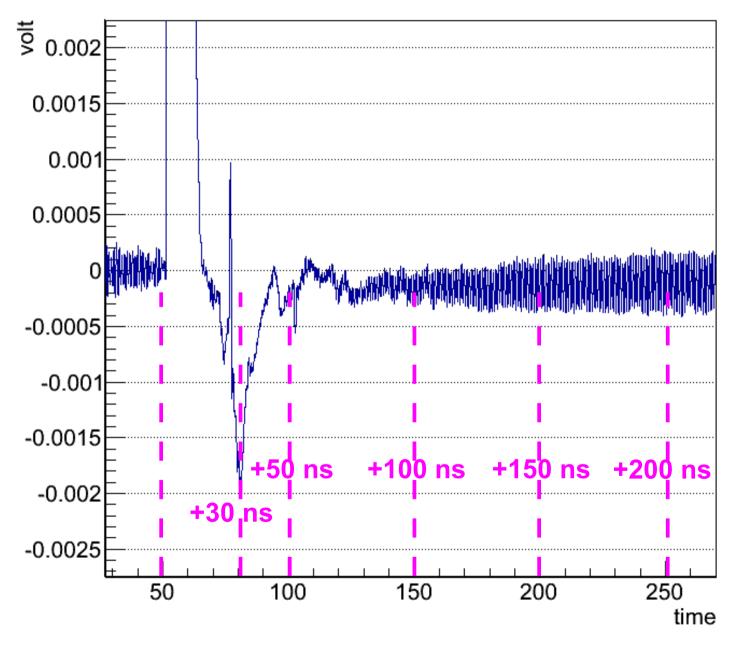
20121110210502_Micron_FZ2852-23_PonN



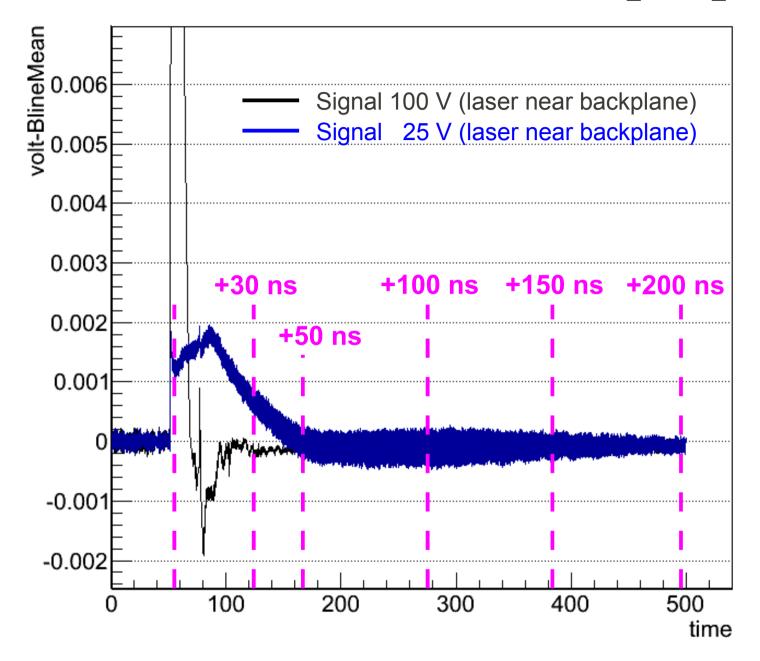
Up to 500 ns recorded in scope. Studying effect of integration time on CCE.

> Longer integration time \rightarrow more undershoot is integrated \rightarrow less charge collected Longer integration time \rightarrow more signal can be collected at lower bias \rightarrow plateau reached before

20121110210502_Micron_FZ2852-23_PonN



Longer integration time \rightarrow more undershoot is integrated \rightarrow less charge collected



Longer integration time \rightarrow more signal can be collected at lower bias \rightarrow plateau reached before

Detectors studied

Micron (taken as "reference"): 256 strips, 80 µm pitch, 1x1 cm²

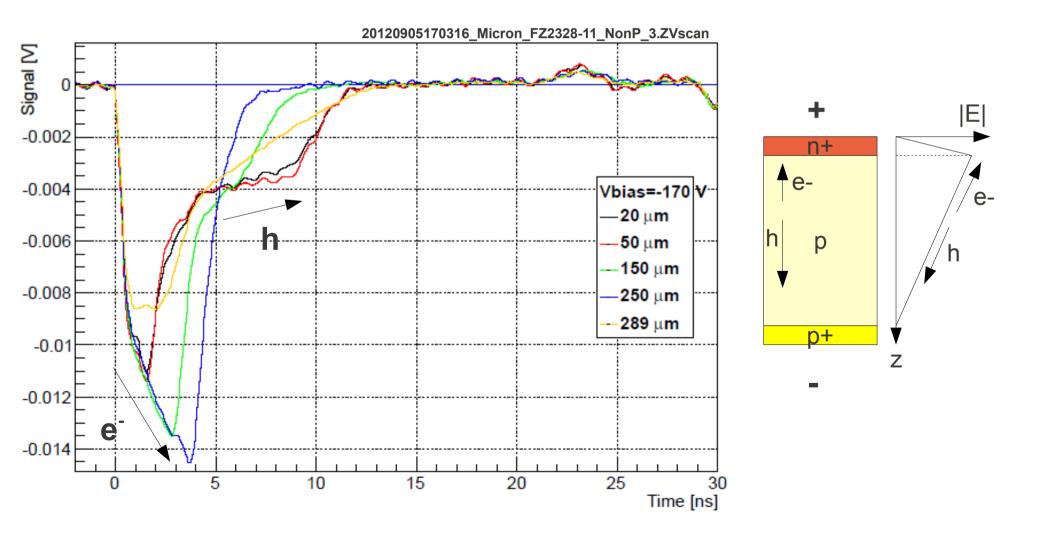
2x N-on-P: FZ2328-11 1x P-on-N: FZ2852-23

Hamamatsu (CMS HPK campaign) Badd: 64 strips, 80 µm pitch, ~2.2x7 mm2

Time resolved pulses at different depths (P bulk)

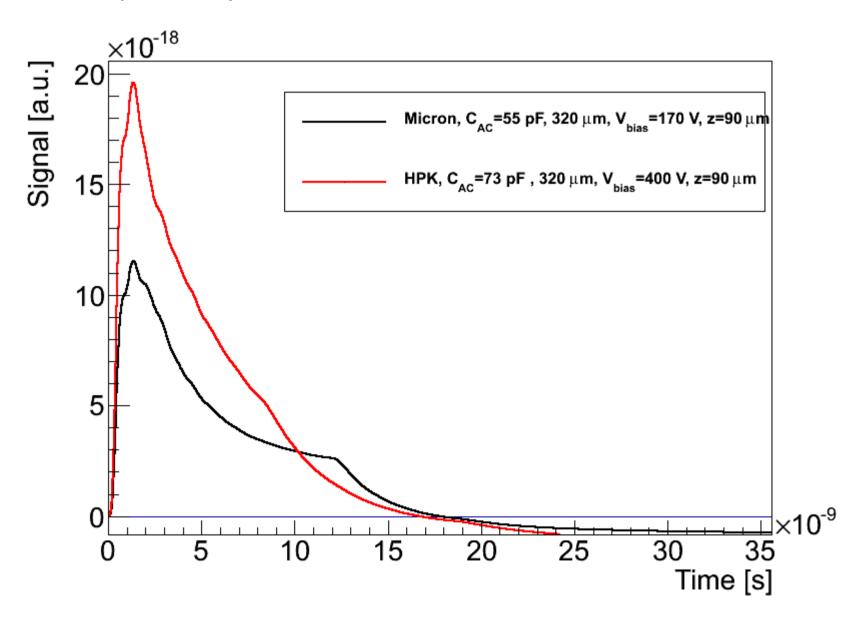
• AC coupling (no bias-T), using Miteq (0.3Mhz-2 Ghz) amplifier, signal measured on digital scope (2.5 Ghz, 20 GSa/s).

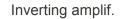
• Clearly seen electrons travelling "against" the increasing electric field, and holes "along" it.

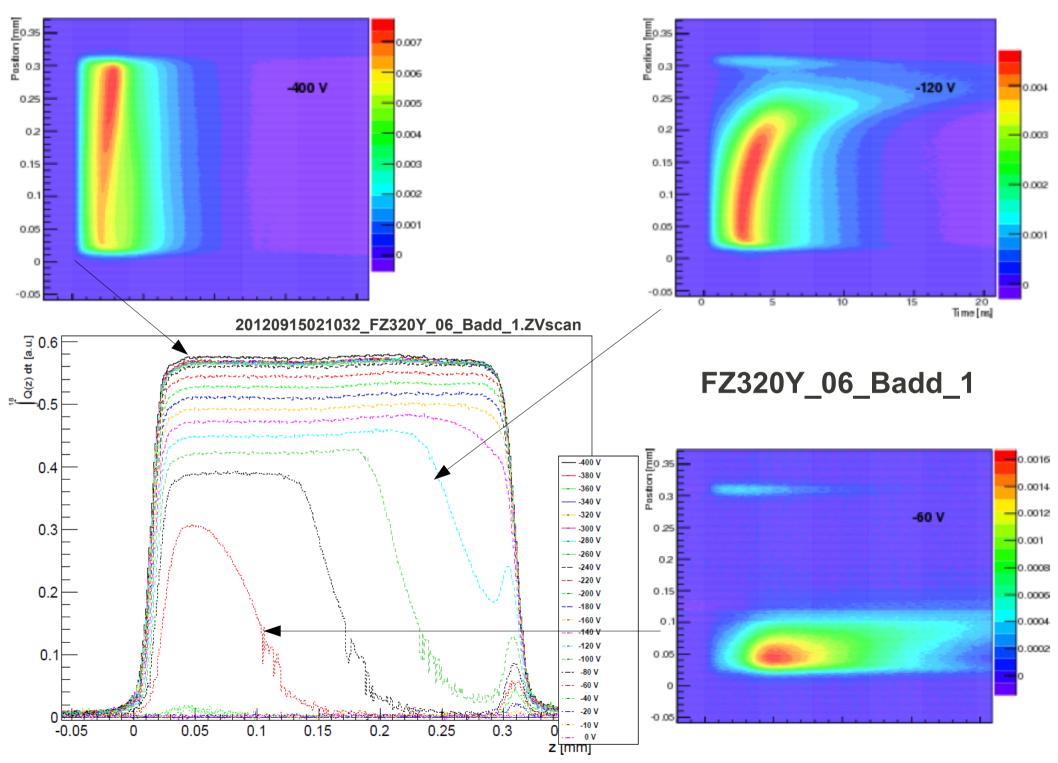


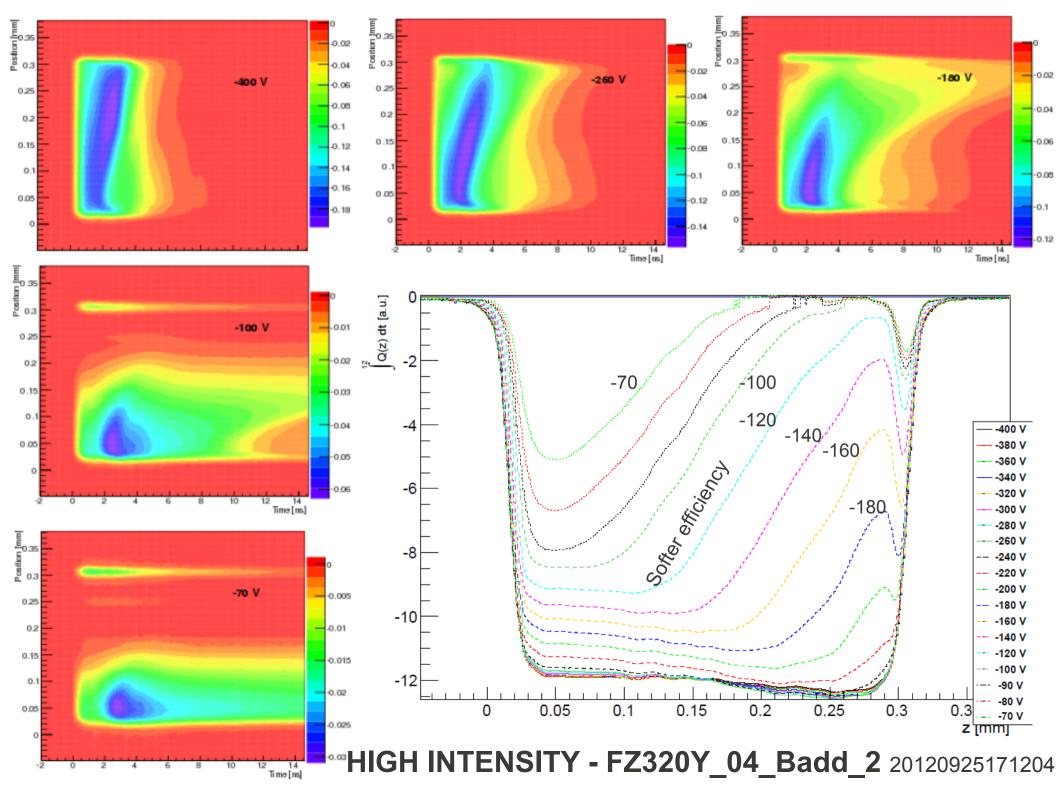
Effect of sensor coupling capacitance

Naïve simulation including detector capacitance and convolution of ideal signal with amplifier response









E-TCT formulae

$$I_{e,h}(t) = Ae_0 N_{e,h} \exp\left(-\frac{t}{\tau_{\text{eff},e,h}}\right) \vec{v}_{e,h}(t) \cdot \vec{E}_w, \quad (1) \quad \mathsf{E}_w = 1/\mathsf{W}$$

$$I(y,t) = I_e(y,t) + I_h(y,t).$$
 (2)

$$I(y, t \sim 0) \approx e_0 A N_{e,h} \frac{v_e(y) + v_h(y)}{W}.$$
 (3)

$$I(y,t \sim 0) \approx \frac{e_0 A N_{e,h}}{W} [\mu_e(E) + \mu_h(E)] E(y).$$
(4)

$$V_{\text{bias}} = \int_0^W E(y) dy$$
 (5) Constrain to fix E(y)

$$Q(y) = \int_0^{t_{\text{int}}} I(y,t)dt \tag{7} \quad \text{Efficiency scan: } Q=Q(y)$$

$$\langle Q \rangle = \frac{1}{W} \int_0^W Q(y) dy.$$
 (8) CCE

From G. Kramberger et al., IEEE Trans. Nucl. Scien., Vol 57, No. 4, August 2010